Docket No.: 50090-301 **PATENT**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

shihiro YAMASHITA, et al.

Serial No.: 09/901,038

Filed: July 10, 2001

Customer Number: 20277

Confirmation Number: 6404

Group Art Unit: 1763

Examiner: M. Crowell

PLASMA PROCESSING SYSTEM IN WHICH WAFER IS RETAINED BY ELECTROSTACTIC For:

CHUCK, PLASMA PROCESSING METHOD AND METHOD OF MANUFACTURING

SEMICONDUCTOR DEVICE

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

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Transmitted herewith is an Amendment in the above-identified application.

No additional fee is required.

Applicant is entitled to small entity status under 37 CFR 1.27

Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	18	20	0	\$18.00 =	\$0.00
Independent Claims	2	3	0	\$86.00 =	\$0.00
		Multiple claims nev	Multiple claims newly presented		
		Fee for extension of time			\$0.00
					\$0.00
		Total of Above Calculations			

Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.

The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

Scott D. Paul

Registration No. 42,984

600 13th Street, N.W. Washington, DC 20005-3096 (202) 756-8000 SDP:kap Facsimile: (202) 756-8087 Date: January 14, 2004

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PLASMA PROCESSING SYSTEM IN WHICH WAFER IS RETAINED BY

ELECTROSTATIC CHUCK, PLASMA PROCESSING METHOD AND METHOD OF

MANUFACTURING SEMICONDUCTOR DEVICE

AMENDMENT

Mail Stop Non-Fee Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the non-final Office Action dated October 17, 2003.